

Substitute form 1449A/PTO			<b>Complete if Known</b>		
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)			Application Number	not yet assigned	
			Filing Date	concurrently herewith	
			First Named Inventor	SooHo Kim	
			Group Art Unit	not yet assigned	
			Examiner Name	not yet assigned	
Sheet	1	of	1	Attorney Docket Number	5649-1215

U.S. PATENTS AND PATENT PUBLICATIONS					
Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		Number	Kind Code (if known)		
AR	1.	US-2001-0012099		Kumagai	08/09/2001
	2.	US-2001-0019407		Sato et al;	09/06/2001
	3.	US-4,861,402		Gordon	08/29/1989
	4.	US-5,745,617		Starodubov et al;	04/28/1998
	5.	US-6,335,126		Kondou et al;	01/01/2001
	6.	US-6,544,914		Kikugawa et al;	04/08/2003
	7.	US 10/623,616			
AR	7.	US-7,001,697		PARK et al.	02/21/2006
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		US-			
		US-			

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Examiner Initials*	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T
		Office	Number	Kind Code (if known)			
AR	8.		1999-0065144		Korean	08/05/1999	
	9.		2001-0052399		Korean	06/25/2001	
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	13.		9-61986		Japanese	03/07/1997	
	14.		2001-272764		Japanese	10/05/2001	

OTHER NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T
AR	15.	N.H. Rizvi; "Femtosecond laser micromachining: Current status and applications, RIKEN Review No. 50 Focused on Laser Precision Microfabrication (LPM 2002), January 2003 pp 1-9	
AR	16.	"Photomask Defect Repair Systems" DRS Series; Industrial - Photomask Defect Repair Systems, Quantronix Products Catalog 2003, pp 24-60.	

Examiner Signature		Date Considered	10/06
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not consid red. Include copy of this form with next communication to applicant.

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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet	A2	of	1
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Application Number	10/775,772
Filing Date	February 9, 2004
First Named Inventor	Soonho Kim
Group Art Unit	1756
Examiner Name	Stephen D. Rosasco
Attorney Docket Number	5649-1215

## U.S. PATENTS AND PATENT PUBLICATIONS

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AB	3.	Translation of an Office Action as issued by the German Patent and Trademark Office . 02/2006	

**Examiner Signature**

Date Considered

10/06

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